

IN THE CLAIMS:

Please amend the claims as follows:

Claim 1 (Currently Amended): A dressing tool ~~which performs the dressing of~~ to dress a working tool that has a doughnut disk-form or circular disk-form working surface, ~~this said dressing tool being characterized by the fact that the tool has~~ having a substantially rectangular dressing surface ~~that performs dressing by~~ for contacting the working surface of the above-mentioned said working tool, and the above-mentioned said dressing surface is disposed so that the centerline of the above-mentioned said dressing surface in the direction of the short sides its long sides of the above-mentioned substantially rectangular shape coincides with the a radial direction passing through the center of the above-mentioned said doughnut disk or circular disk of the above-mentioned said working tool during dressing;

wherein both long sides of said substantially rectangular dressing surface extend in a cone shape diverging away from said centerline in the direction of the long side of said dressing surface such that when said dressing surface is caused to contact said working surface, a contact length between said working surface and said dressing surface is equal at all positions in the radial direction of said working surface.

Claim 2 (Canceled).

Claim 3 (Currently Amended): A dressing apparatus ~~which is characterized by the fact that this apparatus has the~~ with said dressing tool according to Claim 1, and including a working tool holding mechanism which holds [a] said working tool that has a said doughnut disk-form or

circular disk-form working surface, and which causes ~~this~~ said working tool to rotate about an axis that passes through the center of ~~the above-mentioned~~ said doughnut disk or circular disk perpendicular to ~~the above-mentioned~~ said working surface.

Claim 4 (Currently Amended): The dressing apparatus according to Claim 3, ~~which is~~ characterized by the fact that this apparatus has including a plurality of dressing tools, and these said dressing tools are disposed so that ~~the~~ said dressing tools simultaneously dress ~~the above-mentioned~~ said working surface.

Claim 5 (Currently Amended): A working apparatus ~~which has the above-mentioned~~ working tool that is dressed by the dressing tool according to Claim 1 comprising:

a working tool; and

a dressing tool to dress the working tool that has a doughnut disk-form or circular disk-form working surface, said dressing tool having a substantially rectangular dressing surface for contacting the working surface of said working tool, and said dressing surface is disposed so that the centerline of said dressing surface in the direction of its long sides coincides with a radial direction passing through the center of said doughnut disk or circular disk of said working tool during dressing;

wherein both long sides of said substantially rectangular dressing surface extend in a cone shape diverging away from said centerline in the direction of the long side of said dressing surface such that when said dressing surface is caused to contact said working surface, a contact

length between said working surface and said dressing surface is equal at all positions in the radial direction of said working surface; and

wherein said working tool is dressed by said dressing tool.

Claim 6 (Currently Amended): A working apparatus ~~which has the above mentioned~~ working tool that is dressed by the dressing apparatus according to Claim 3 comprising:

a working tool; and

a dressing apparatus with a dressing tool to dress the working tool that has a doughnut disk-form or circular disk-form working surface, said dressing tool having a substantially rectangular dressing surface for contacting the working surface of said working tool, and said dressing surface is disposed so that the centerline of said dressing surface in the direction of its long sides coincides with a radial direction passing through the center of said doughnut disk or circular disk of said working tool during dressing;

wherein both long sides of said substantially rectangular dressing surface extend in a cone shape diverging away from said centerline in the direction of the long side of said dressing surface such that when said dressing surface is caused to contact said working surface, a contact length between said working surface and said dressing surface is equal at all positions in the radial direction of said working surface;

a working tool holding mechanism which holds said working tool that has said doughnut disk-form or circular disk-form working surface, and which causes said working tool to rotate about an axis that passes through the center of said doughnut disk or circular disk perpendicular to said working surface; and

wherein said working tool is dressed by said dressing apparatus.

Claim 7 (Withdrawn): A dressing tool which is used to dress the working surface of a working tool that has a circular outer circumference, this dressing tool being characterized by the fact that the dressing tool comprises a dressing surface which is constructed from a circular region that has a first cutting capacity per unit area, and an annular region that is concentric with the above-mentioned circular region and that has a second cutting capacity per unit area that is higher than the above-mentioned first cutting capacity per unit area, the diameter of the above-mentioned circular region of the above-mentioned dressing surface is greater than the effective use width within the radius of the above-mentioned working surface, and the external diameter of the above-mentioned annular region of the above-mentioned dressing surface is substantially half of the external diameter of the above-mentioned working surface.

Claim 8 (Withdrawn): A dressing tool which is used to dress the working surface of a working tool that has a circular outer circumference, this dressing tool being characterized by the fact that the dressing tool comprises a dressing surface which is constructed from a circular region in which abrasive grains are distributed at a first mean distribution density, and an annular region which is concentric with the above-mentioned circular region, and in which abrasive grains are distributed at a second mean distribution density that is higher than the above-mentioned first mean distribution density, the diameter of the above-mentioned circular region of the above-mentioned dressing surface is greater than the effective use width within the radius of the above-mentioned working surface, and the external diameter of the above-mentioned annular

region of the above-mentioned dressing surface is substantially half of the external diameter of the above-mentioned working surface.

Claim 9 (Withdrawn): The dressing tool according to Claim 8, which is characterized by the fact that the above-mentioned first mean distribution density is 10% to 50% of the above-mentioned second mean distribution density.

Claim 10 (Withdrawn): A dressing apparatus which is characterized by the fact that this dressing apparatus comprises the dressing tool according to Claim 7, and a rotational mechanism which causes this dressing tool to rotate.

Claim 11 (Withdrawn): A dressing method which dresses the working surface of a working tool supported on a substrate by causing contact between this working surface and the dressing surface of a dressing tool and causing relative motion between the above-mentioned substrate and the above-mentioned dressing tool, this dressing method being characterized by the fact that this method comprises a setting stage in which the relative inclination of the above-mentioned dressing surface with reference to the above-mentioned substrate is adjusted to a desired inclination and set, and a dressing stage in which the above-mentioned working surface is dressed while maintaining the above-mentioned relative inclination set in the above-mentioned setting stage.

Claim 12 (Withdrawn): The dressing method according to Claim 11, which is characterized by the fact that the above-mentioned setting stage includes a stage in which information corresponding to the surface shape of the above-mentioned working surface is obtained, and a stage in which the above-mentioned relative inclination is adjusted and set on the basis of the above-mentioned information.

Claim 13 (Withdrawn): The dressing method according to Claim 11, which is characterized by the fact that the above-mentioned setting stage and the above-mentioned dressing stage are alternately repeated a multiple number of times each until the surface shape of the above-mentioned working surface becomes a surface shape that is within the permissible range.

Claim 14 (Withdrawn): The dressing method according to Claim 11, which is characterized by the fact that the dressing of the above-mentioned working surface in the above-mentioned dressing stage is performed in a state in which a portion of the above-mentioned dressing surface protrudes from the circumference of the above-mentioned working surface.

Claim 15 (Withdrawn): The dressing method according to Claim 11, which is characterized by the fact that the above-mentioned relative inclination is an inclination about a specified axial line that is substantially perpendicular to a straight line passing through the vicinity of the center of the above-mentioned working surface and the vicinity of the center of the above-mentioned dressing surface.

Claim 16 (Withdrawn): A dressing apparatus which dresses the working surface of a working tool supported on a substrate by causing contact between this working surface and the dressing surface of a dressing tool and causing relative motion between the above-mentioned substrate and the above-mentioned dressing tool, this dressing apparatus being characterized by the fact that the apparatus comprises an inclination adjustment mechanism that can adjust the relative inclination of the above-mentioned dressing surface with reference to the above-mentioned substrate to a desired inclination and set this inclination, and a moving mechanism which dresses the above-mentioned working surface by causing relative motion between the above-mentioned substrate and the above-mentioned dressing tool while maintaining the above-mentioned relative inclination set by the above-mentioned inclination adjustment mechanism.

Claim 17 (Withdrawn): The dressing apparatus according to Claim 16, which is characterized by the fact that the dressing apparatus is an apparatus that dresses the working surface of a working tool that has a circular outer circumference, the above-mentioned dressing tool comprises a dressing surface which is constructed from a circular region that has a first cutting capacity per unit area, and an annular region that is concentric with the above-mentioned

circular region and that has a second cutting capacity per unit area that is higher than the above-mentioned first cutting capacity per unit area, the diameter of the above-mentioned circular region of the above-mentioned dressing surface is greater than the effective use width within the radius of the above-mentioned working surface, and the external diameter of the above-mentioned annular region of the above-mentioned dressing surface is substantially half of the external diameter of the above-mentioned working surface.

Claim 18 (Withdrawn): The dressing apparatus according to Claim 16, which is characterized by the fact that the dressing apparatus comprises a control part that operates the above-mentioned inclination adjustment mechanism on the basis of information corresponding to the surface shape of the above-mentioned working surface so that the above-mentioned relative inclination is a desired inclination.

Claim 19 (Withdrawn): The dressing apparatus according to Claim 18, which is characterized by the fact that the dressing apparatus comprises a measuring part that acquires the above-mentioned information.

Claim 20 (Withdrawn): A dressing apparatus which dresses the working surface of a working tool supported on a substrate by causing contact between this working surface and the dressing surface of a dressing tool and causing relative motion between the above-mentioned substrate and the above-mentioned dressing tool, this dressing apparatus being characterized by the fact that the apparatus comprises an inclination adjustment mechanism that can adjust the

relative inclination of the above-mentioned dressing surface with reference to the above-mentioned substrate to a desired inclination and set this inclination, a moving mechanism which dresses the above-mentioned working surface by causing relative motion between the above-mentioned substrate and the above-mentioned dressing tool while maintaining the above-mentioned relative inclination set by the above-mentioned inclination adjustment mechanism, a measuring part which acquires information corresponding to the surface shape of the above-mentioned working surface, and a control part which, in response to specified command signals, (i) causes the above-mentioned dressing to be performed by operating the above-mentioned moving mechanism, (ii) makes a judgment as to whether or not the above-mentioned relative inclination that is currently set is the desired inclination on the basis of the above-mentioned information acquired by the above-mentioned measuring part following the dressing performed in the above-mentioned (i), (iii) ends the adjustment of the above-mentioned relative inclination in cases where it is judged in the above-mentioned (ii) that the currently set inclination is the desired inclination, and (iv) repeats the operation from the above-mentioned (i) on after operating the above-mentioned inclination adjustment mechanism so that the above-mentioned relative inclination is adjusted to the desired inclination or an inclination that approaches this desired inclination in cases where it is judged in the above-mentioned (ii) that the currently set inclination is not the desired inclination.

Claim 21 (Withdrawn): The dressing apparatus according to Claim 20, which is characterized by the fact that the dressing apparatus is an apparatus that dresses the working surface of a working tool that has a circular outer circumference, the above-mentioned dressing tool comprises a dressing surface which is constructed from a circular region that has a first cutting capacity per unit area, and an annular region that is concentric with the above-mentioned circular region and that has a second cutting capacity per unit area that is higher than the above-mentioned first cutting capacity per unit area, the diameter of the above-mentioned circular region of the above-mentioned dressing surface is greater than the effective use width within the radius of the above-mentioned working surface, and the external diameter of the above-mentioned annular region of the above-mentioned dressing surface is substantially half of the external diameter of the above-mentioned working surface.

Claim 22 (Withdrawn): The dressing apparatus according to Claim 16, which is characterized by the fact that the dressing of the above-mentioned working surface is performed in a state in which a portion of the above-mentioned dressing surface protrudes from the circumference of the above-mentioned working surface.

Claim 23 (Withdrawn): The dressing apparatus according to Claim 20, which is characterized by the fact that the dressing of the above-mentioned working surface is performed in a state in which a portion of the above-mentioned dressing surface protrudes from the circumference of the above-mentioned working surface.

Claim 24 (Withdrawn): The dressing apparatus according to Claim 16, which is characterized by the fact that the above-mentioned relative inclination is an inclination about a specified axial line that is substantially perpendicular to a straight line passing through the vicinity of the center of the above-mentioned working surface and the vicinity of the center of the above-mentioned dressing surface.

Claim 25 (Withdrawn): The dressing apparatus according to Claim 20, which is characterized by the fact that the above-mentioned relative inclination is an inclination about a specified axial line that is substantially perpendicular to a straight line passing through the vicinity of the center of the above-mentioned working surface and the vicinity of the center of the above-mentioned dressing surface.

Claim 26 (Withdrawn): A working apparatus which comprises a working tool that has a working surface, and a holding part that holds the workpiece, and which works the above-mentioned workpiece by applying a load between the above-mentioned working surface of the above-mentioned working tool and the above-mentioned workpiece and causing the relative motion of the above-mentioned working tool and the above-mentioned workpiece, this working apparatus being characterized by the fact that the above-mentioned working surface is dressed by the dressing method according to Claim 11.

Claim 27 (Withdrawn): A working apparatus which comprises a working tool that has a working surface, and a holding part that holds workpiece, and which works the above-mentioned workpiece by applying a load between the above-mentioned working surface of the above-mentioned working tool and the above-mentioned workpiece and causing the relative motion of the above-mentioned working tool and the above-mentioned workpiece, this working apparatus being characterized by the fact that the above-mentioned working surface is dressed by the dressing apparatus according to Claim 16.

Claim 28 (Withdrawn): A working apparatus which comprises a working tool that has a working surface, and a holding part that holds the workpiece, and which works the above-mentioned workpiece by applying a load between the above-mentioned working surface of the above-mentioned working tool and the above-mentioned workpiece and causing the relative motion of the above-mentioned working tool and the above-mentioned workpiece, this working apparatus being characterized by the fact that the above-mentioned working surface is dressed by the dressing apparatus according to Claim 20.

Claim 29 (Withdrawn): A working apparatus which comprises a working tool that has a working surface, and a holding part that holds the workpiece, and which works the above-mentioned workpiece by applying a load between the above-mentioned working surface of the above-mentioned working tool and the above-mentioned workpiece and causing the relative motion of the above-mentioned working tool and the above-mentioned workpiece, this working

apparatus being characterized by the fact that the apparatus comprises the dressing apparatus according to Claim 16.

Claim 30 (Withdrawn): A working apparatus which comprises a working tool that has a working surface, and a holding part that holds the workpiece, and which works the above-mentioned workpiece by applying a load between the above-mentioned working surface of the above-mentioned working tool and the above-mentioned workpiece and causing the relative motion of the above-mentioned working tool and the above-mentioned workpiece, this working apparatus being characterized by the fact that the apparatus comprises the dressing apparatus according to Claim 20.

Claim 31 (Original): A semiconductor device manufacturing method which is characterized by the fact that this method has a process in which the surface of a semiconductor wafer is flattened using the working apparatus according to Claim 5.

Claim 32 (Original): A semiconductor device manufacturing method which is characterized by the fact that this method has a process in which the surface of a semiconductor wafer is flattened using the working apparatus according to Claim 6.

Claim 33 (Withdrawn): A semiconductor device manufacturing method which is characterized by the fact that this method has a process in which the surface of a semiconductor wafer is flattened using the working apparatus according to Claim 26.

Claim 34 (Withdrawn): A semiconductor device manufacturing method which is characterized by the fact that this method has a process in which the surface of a semiconductor wafer is flattened using the working apparatus according to Claim 27.

Claim 35 (Withdrawn): A semiconductor device manufacturing method which is characterized by the fact that this method has a process in which the surface of a semiconductor wafer is flattened using the working apparatus according to Claim 28.

Claim 36 (Withdrawn): A semiconductor device manufacturing method which is characterized by the fact that this method has a process in which the surface of a semiconductor wafer is flattened using the working apparatus according to Claim 29.

Claim 37 (Withdrawn): A semiconductor device manufacturing method which is characterized by the fact that this method has a process in which the surface of a semiconductor wafer is flattened using the working apparatus according to Claim 30.